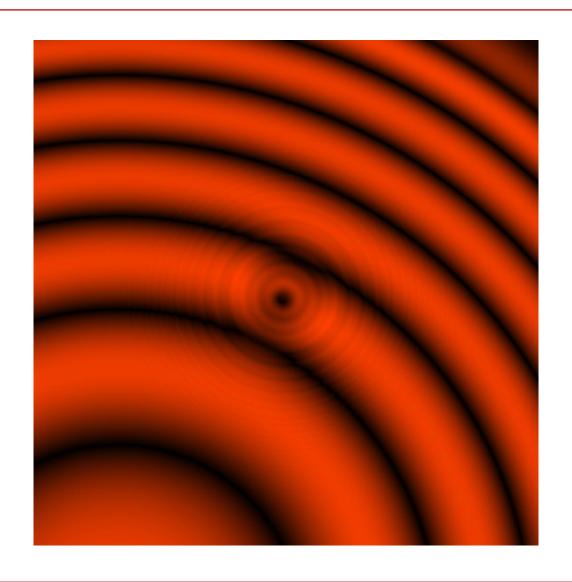


### **Mach-Zehnder Interferometer with Small Defects**

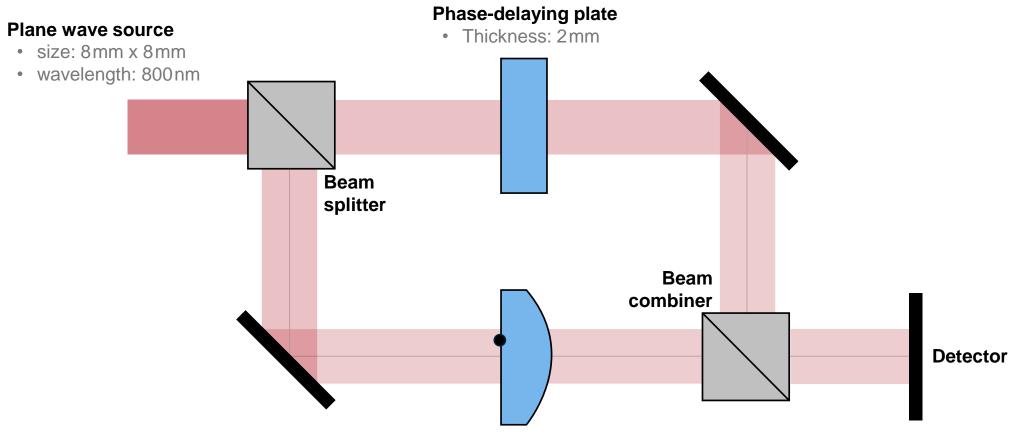
### **Abstract**



In real optical systems, component defects from exposure will affect overall performance. From a simulation perspective, propagating large fields with diffraction effects caused by tiny defects is highly challenging. This use case demonstrates VirtualLab Fusions multi-scale simulation approach by introducing small defects into a Mach-Zehnder interferometer and analyzing the resulting interference pattern.

# **Application Scenario**

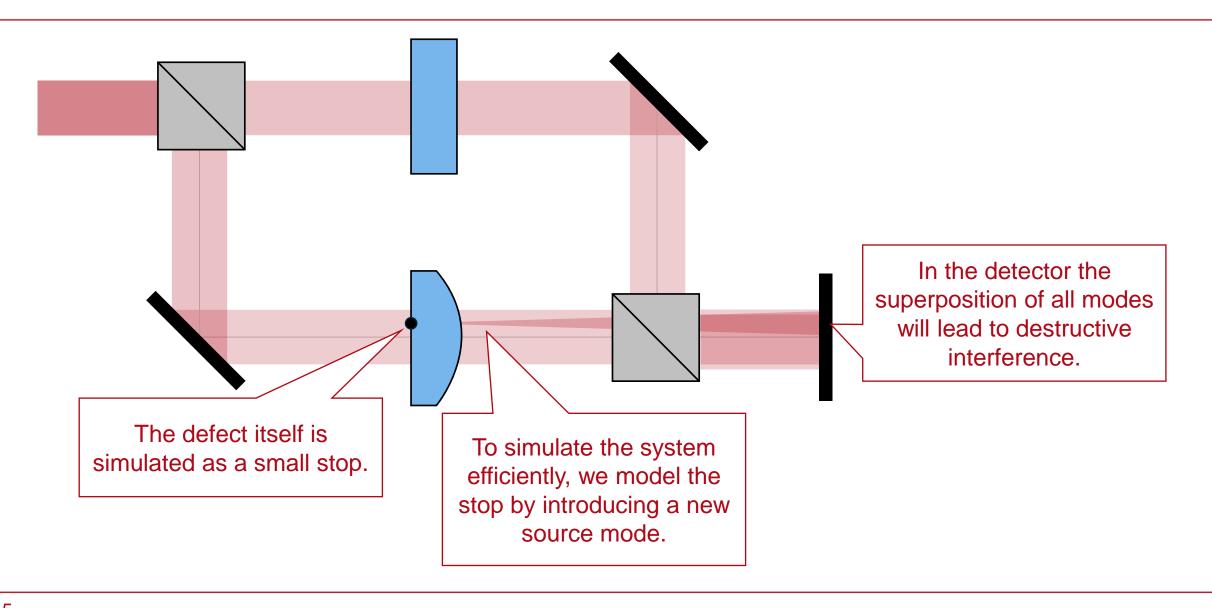
## **Application Scenario: System**



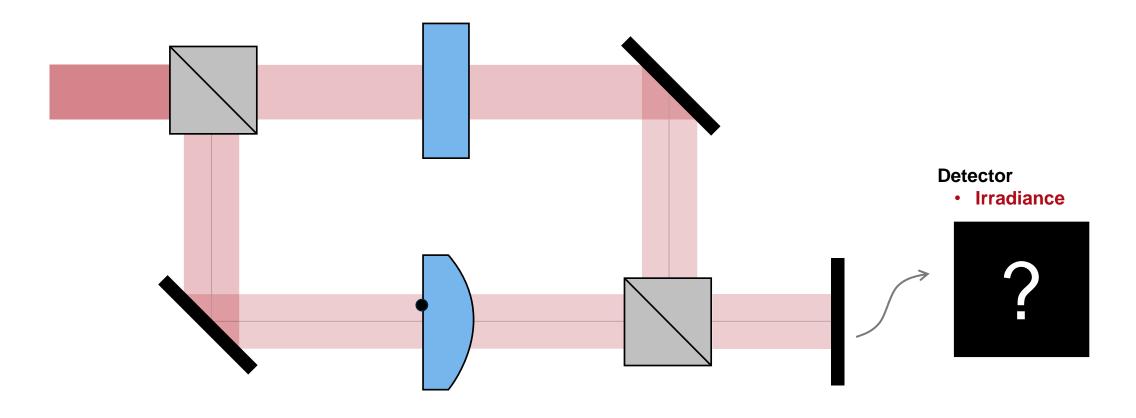
#### Plane-convex lens with defect

- Radius of curvature (convex-part): 1 m
- Center thickness: 2mm
- Size of defect: 50 μm 300 μm

## **Application Scenario: System**



## **Application Scenario: Task**



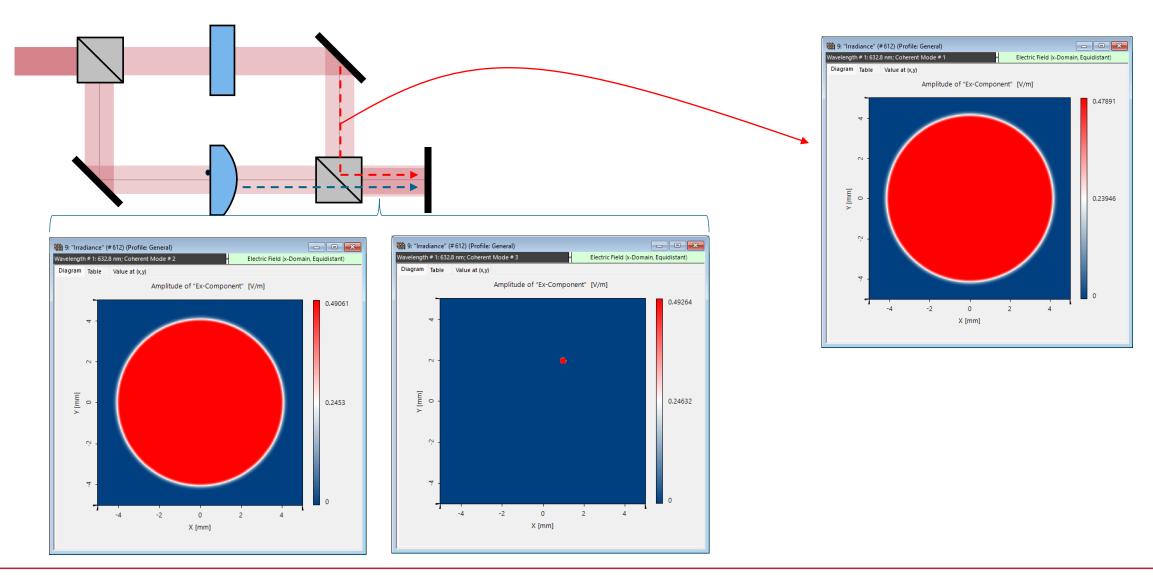
**Task 1:** Compare the detector-plane irradiance for a system with a 300 µm defect to a case with no defect.

**Task 2:** Reduce the defect size to 100 µm and 50 µm and calculate irradiance pattern.

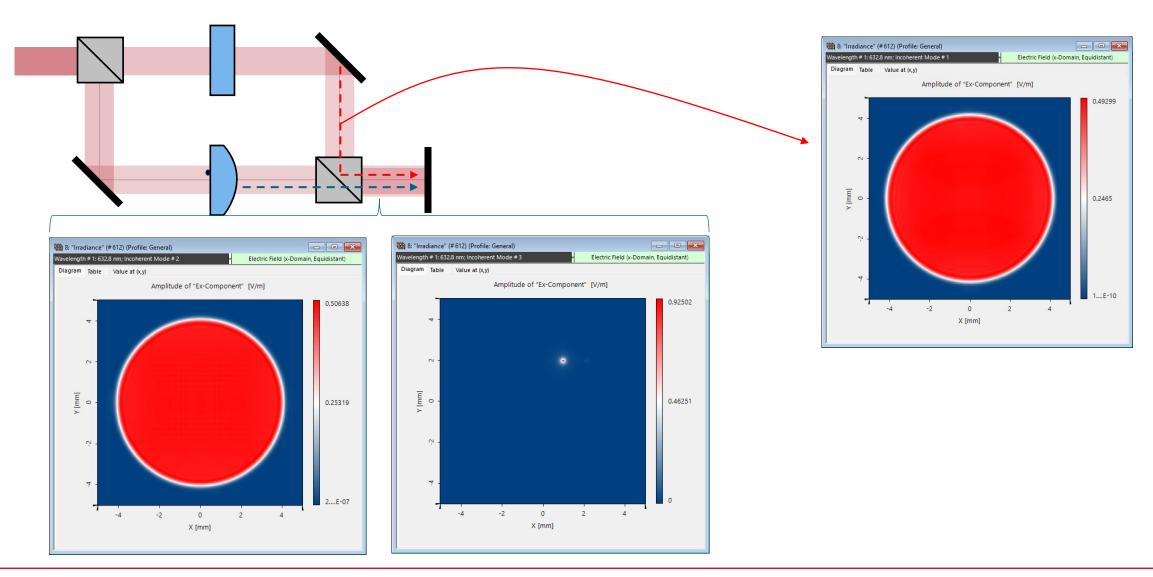
## Results

**Task 1: Compare Irradiance Pattern** 

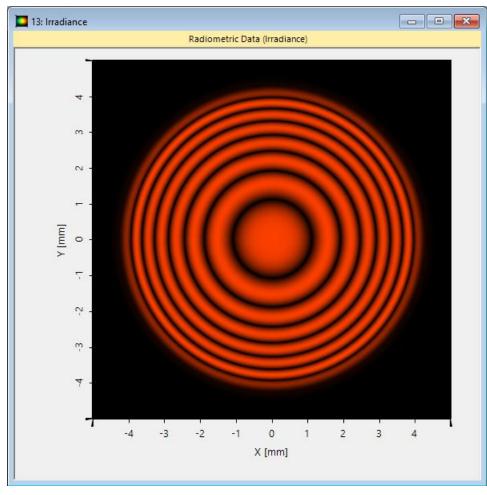
## Field per Mode at Detector (without Diffraction)



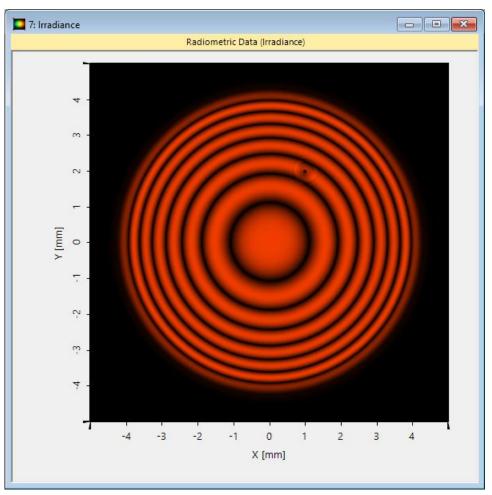
## Field per Mode at Detector (with Diffraction)



## **Comparison (Modes Added)**

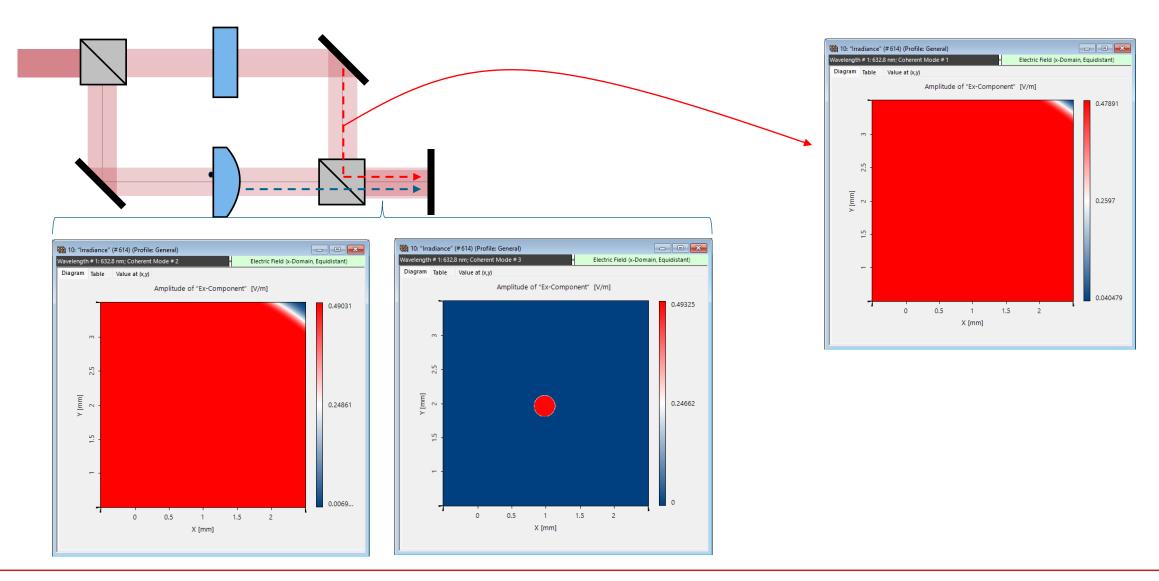


Irradiance without consideration of the defect (only perturbated fields added)

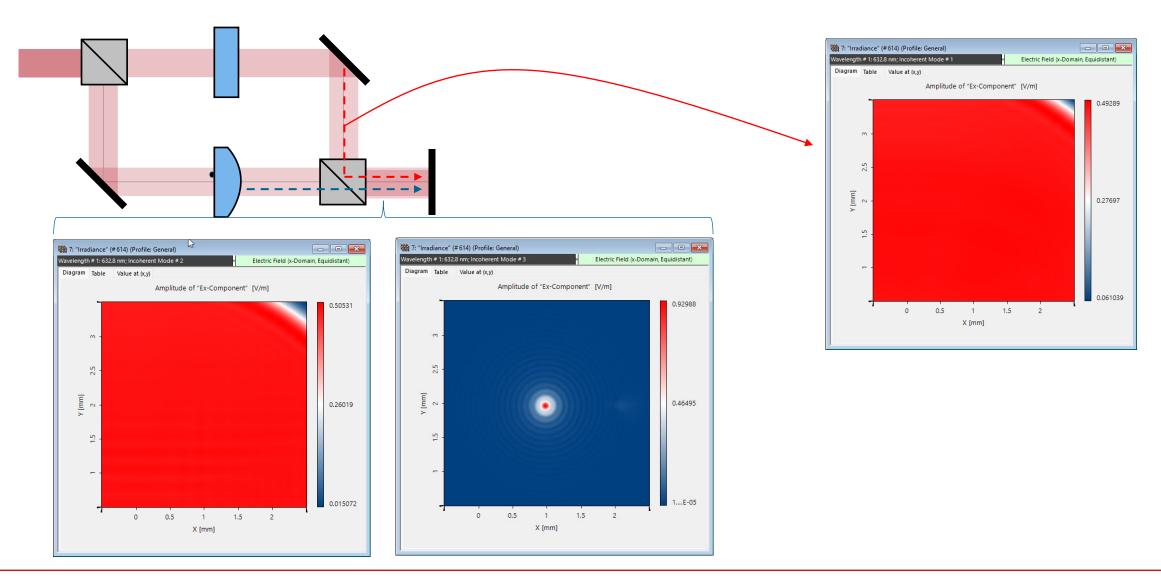


Irradiance with consideration of defect (all fields added)

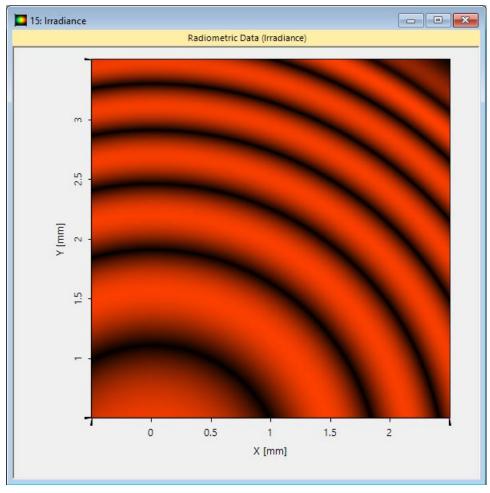
## Field per Mode at Detector (without Diffraction) - Zoom



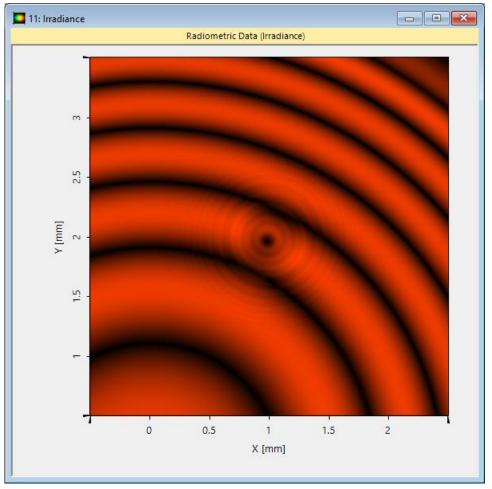
## Field per Mode at Detector (with Diffraction)- Zoom



## Comparison (Modes Added) - Zoom



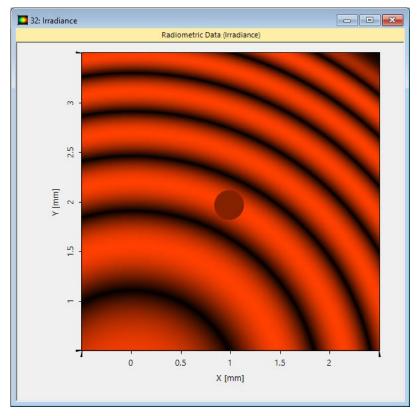
Irradiance without consideration of the defect (only perturbated fields added)

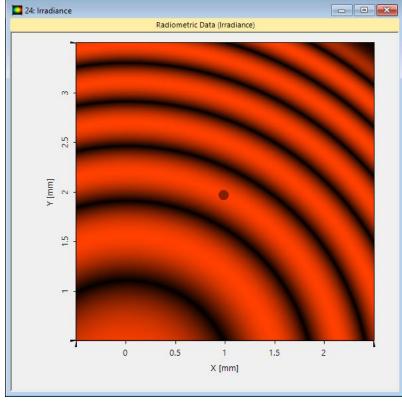


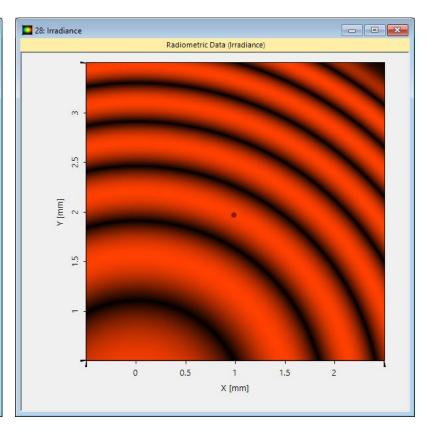
Irradiance with consideration of defect (all fields added)

## **Task 2: Reduce Defect Size**

## Variation of Defect Size without Considering Diffraction



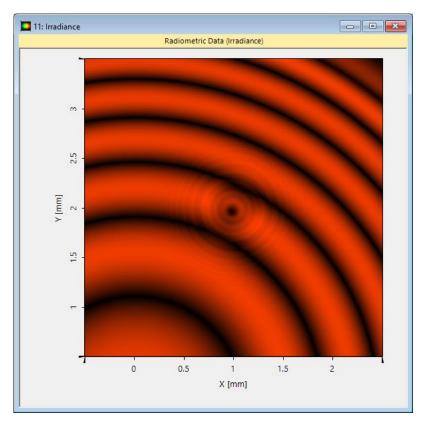


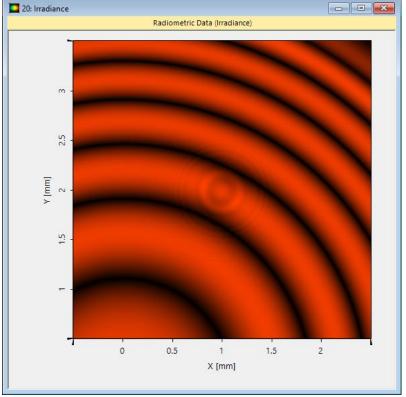


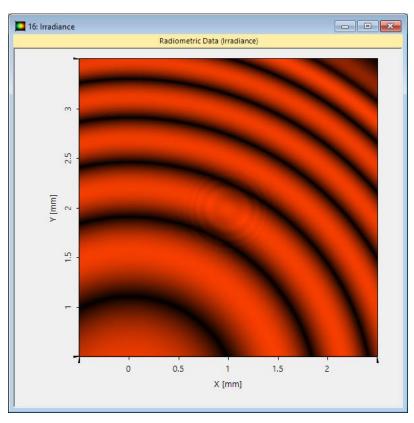
300 µm defect size 100 µm defect size 50 µm defect size

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## Variation of Defect Size with Considering Diffraction







300 µm defect size

100 µm defect size

50 µm defect size

## **Workflows**

### **LP Mode Source**

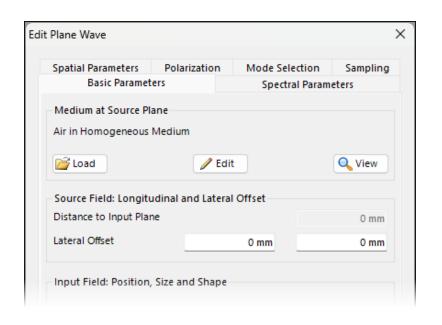
Source selection

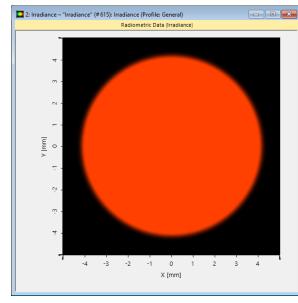
System setup

**Detector selection** 

### Getting it done in VirtualLab Fusion:

Plane Wave





## **System Setup**

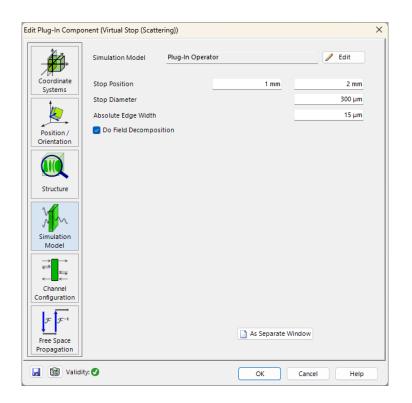
Source selection

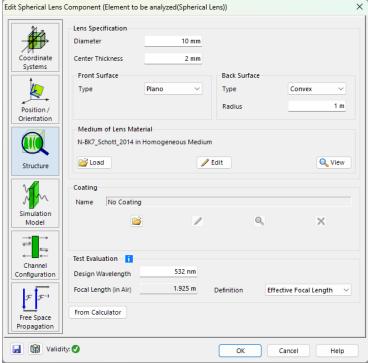
System setup

**Detector selection** 

#### Getting it done in VirtualLab Fusion:

- Model lens by Spherical Lens component
- Include defect by Virtual Stop component





### **Detector Selection**

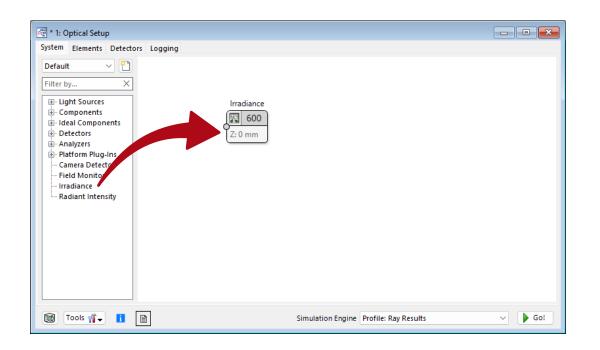
Source selection

System setup

Detector selection

### Getting it done in VirtualLab Fusion:

Add Irradiance detector to your system.

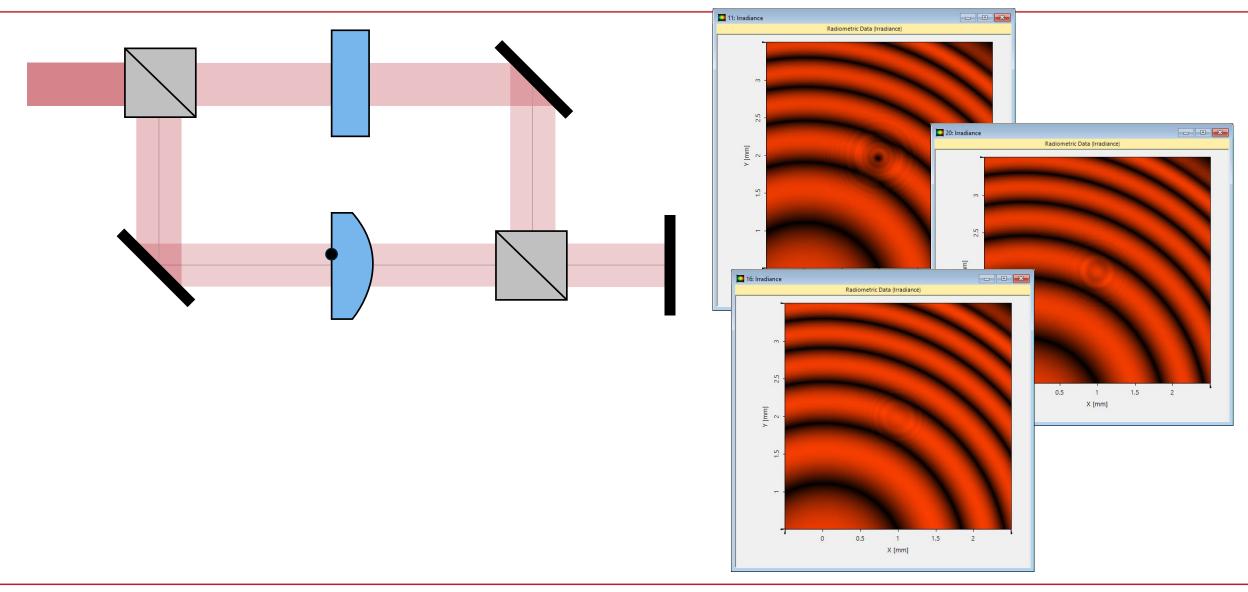


### **Document Information**

Title	Mach-Zehnder Interferometer with Small Defects
Document code	USC.0464
Publication date	05.09.2025
Required packages	
Software version	2025.2 (Build 1.118)*
Category	Use Case
Further reading	<ul> <li>Laser-Based Michelson Interferometer and Interference Fringe Exploration</li> <li>Fizeau Interferometer for Optical Testing</li> </ul>

<sup>\*</sup> The files attached to this document require the specific version or later.

# **Marketing Picture**



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